



IFW

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q79976

OSHIMA, Yuichi

Appln. No.: 10/779,740

Group Art Unit: 2818

Confirmation No.: 2078

Examiner: NGO, Ngan V.

Filed: February 18, 2004

For: NITRIDE SEMICONDUCTOR SUBSTRATE AND ITS PRODUCTION METHOD

RESPONSE TO RESTRICTION REQUIREMENT

MAIL STOP AMENDMENT

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Responsive to the outstanding Restriction Requirement of June 22, 2005, Applicant elects the claims of Group I, claims 1-7, drawn to a semiconductor device, without traverse.

Respectfully submitted,

Peter D. Olexy, P.C.
Registration No. 24,513

SUGHRUE MION, PLLC
Telephone: (202) 293-7060
Facsimile: (202) 293-7860

WASHINGTON OFFICE

23373

CUSTOMER NUMBER

Date: July 12, 2005